Attorney Docket No. 008401 04

EXPRESS MAIL CERTIFICATE

Date 23-03 Label No. 
I hereby certify that, on the date indicated above I deposited this peper or fee and every paper referred to therein with the U.S. Postal Service and that it was addressed for delivery to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 by "Express Mail Post Office to Addresses" service.



Mail Stop Patent Application Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450



In re Application of: Kenneth S. Collins, Hiroji Hanawa, Kartik Ramaswamy,
Andrew Nguyen, Amir Al-Bayati, Biagio Gallo, and Gonzalo
Antonio Monroy

Entitled: PLASMA IMMERSION ION IMPLANTATION PROCESS USING A A CAPACITIVELY COUPLED PLASMA SOURCE HAVING LOW DISSOCIATION AND LOW MINIMUM PLASMA VOLTAGE

Attorney Docket No.: 008401 04

Sir:

Enclosed herewith for filing is a patent application entitled PLASMA IMMERSION ION IMPLANTATION PROCESS USING A CAPACITIVELY COUPLED PLASMA SOURCE HAVING LOW DISSOCIATION AND LOW MINIMUM PLASMA VOLTAGE including 141 pages of specification, 87 claims and abstract, and 85 sheets of drawings (Figures 1-112).

This application is being filed missing parts and specifically without a declaration by the inventors and without a filing fee. The application is being filed in the names of the inventors, Kenneth S. Collins, Hiroji Hanawa, Kartik Ramaswamy, Andrew Nguyen, Amir Al-Bayati, Biagio Gallo, and Gonzalo Antonio Monroy.

Please address all correspondence to:

Patent Counsel, M/S 2061 Legal Affairs Dept. Applied Materials, Inc. P.O. Box 450-A Santa Clara, CA 95035

Please direct all telephone inquiries to: Robert M. Wallace (805) 644-4035

Dated: August 22, 2003

Respectfully submitted,

Robert M. Wallace Reg. No. 29,119

Attorney for Applicant(s)